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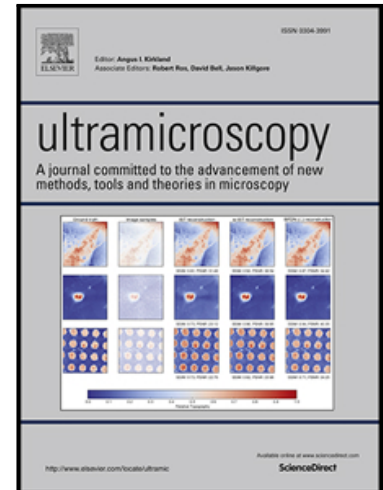
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Highlights

- STEM images are simulated using the frozen phonon and absorptive potential model.
- Both models are compared in a quantitative manner.
- A comparison is made in terms of integrated intensity and precision.
- For high angles and large thicknesses, the AP model underestimates the integrated intensity.
- Comparable results are predicted for the precision with which atomic columns can be located.

ACCEPTED MANUSCRIPT

Frozen lattice and absorptive model for high angle annular dark field scanning transmission electron microscopy: a comparison study in terms of integrated intensity and atomic column position measurement

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Abstract

In this paper, both the frozen lattice (FL) and the absorptive potential (AP) approximation models are compared in terms of the integrated intensity and the precision with which atomic columns can be located from an image acquired using high angle annular dark field (HAADF) scanning transmission electron microscopy (STEM). The comparison is made for atoms of Cu, Ag, and Au. The integrated intensity is computed for both an isolated atomic column and an atomic column inside an FCC structure. The precision has been computed using the so-called Cramér-Rao Lower Bound (CRLB), which provides a theoretical lower bound on the variance with which parameters can be estimated. It is shown that the AP model results into accurate measurements for the integrated intensity only for small detector ranges under relatively low angles and for small thicknesses. In terms of the attainable precision, both methods show similar results indicating picometer range precision under realistic experimental conditions.

Keywords: Multislice simulations; Thermal diffuse scattering; Frozen phonon; Frozen lattice; Absorptive potential; STEM

1. Introduction

Material properties are strongly connected to the electronic structure, which in turn critically depend on the atom positions [1, 2]. It is well known that extremely small changes in the local atomic structure may result into significant changes in their properties [3, 4, 5]. Therefore, development of quantitative techniques to measure the atomic arrangement of projected atomic columns or individual atoms with sub-picometre precision is required. The enormous progress in aberration-corrected scanning transmission electron microscopy (STEM) makes it a powerful tool that enables structure characterisation and chemical mapping at the atomic scale with high precision [6, 7]. A key imaging mode is high angle annular dark field (HAADF) STEM, where the collected signal is sensitive to the structural and chemical composition.

Although modern STEM is capable of reaching sub-Angstrom resolution, quantitative structure determination requires accurate image simulations combined with statistical parameter estimation. The simulations are needed in order to understand the quantum mechanical nature of the

15 electron-specimen interaction, and statistical parameter estimation is needed in order to quantify
 16 or more correctly to estimate unknown structure parameters from STEM images. For high-angle
 17 scattering, the intensity is mainly dominated by Rutherford and thermal diffuse scattering (TDS).
 18 Therefore, most of the HAADF signal emitted by each atom contributes incoherently [8, 9]. This
 19 diffuse intensity, resulting from the phonon scattering, can be included in the multislice simu-
 20 lations by using realistic phonon calculations (frozen phonon) or by the Einstein model (frozen
 21 lattice (FL)). However, both models require repeated MS calculations for a large number of dif-
 22 ferent configurations of the specimen. This process requires an enormous amount of computer
 23 calculations and is time-consuming, especially, for simulations involving high angle scattering
 24 where a dense sampling is required. As an alternative method, which is computationally less in-
 25 tensive and which requires only a single configuration for the specimen, the Absorptive Potential
 26 (AP) approximation model is often included into the MS algorithm [10, 11, 12, 13].

27
 28 The main objective of this paper is to investigate to which extent the faster but less reliable
 29 absorptive model can tolerably be used to measure parameters from HAADF STEM images,
 30 which are often used to quantify the underlying structure. Therefore, in this paper, we will study
 31 the difference in intensities between the FL and the AP models for HAADF STEM images. First,
 32 we will compare the total integrated intensity scattered toward the annular STEM detector of an
 33 isolated atomic column and an atomic column inside an FCC structure. Next, the theoretical
 34 limit with which an atomic column can be located in two dimensions (2D) based on HAADF
 35 STEM images is explored. The calculation of the attainable precision is based on the concept
 36 of Fisher information and expresses a theoretical lower bound on the attainable variance. This
 37 study has been done for three different atom types, selected as a function of their scattering factor
 38 amplitude: weakly scattering atoms, e.g. copper (Cu); medium scattering atoms, e.g. silver (Ag);
 39 and strongly scattering atoms, e.g. gold (Au).

40
 41 The organisation of this paper is as follow. In section 2, the electron-specimen interaction
 42 theory, the methods used to simulate STEM images, and the theory for computing the attainable
 43 precision are described. In section 3, the parameters used for the STEM simulations are sum-
 44 marised. In Section 4, the numerical results are discussed. Finally, in section 5, conclusions are
 45 drawn.

46 2. Theoretical background

47 STEM image simulations are based on a full quantum mechanical treatment of the dynamical
 48 scattering that occurs during electron propagation through the specimen [12]. It has been
 49 demonstrated that the non-relativistic Schrödinger equation with the relativistically correct mass
 50 and wavelength yields accurate results for typical energy ranges used in the transmission electron
 51 microscope [14, 15, 16, 17]. In the paraxial approximation, that is, parallel to the optical axis
 52 (z -axis), this equation may be written as [18]

$$\left[\Delta_{xy} + \frac{4\pi i}{\lambda} \frac{\partial}{\partial z} + \frac{2me}{\hbar^2} V(\mathbf{r}) \right] \psi(\mathbf{r}) = 0 \quad (1)$$

53 where

$$V(\mathbf{r}) = \sum_i V_i(\mathbf{r} - \mathbf{r}_i) \quad (2)$$

54 is the electrostatic Coulomb potential, which is given by the sum of the electrostatic potentials of
 55 all atoms in the specimen. Furthermore, $\mathbf{r} = (x, y, z)$ is a set of three-dimensional (3D) Cartesian
 56 coordinates, $\hbar = h/2\pi$ is Planck's constant divided by 2π , $m = \gamma m_0$ is the relativistic mass of the
 57 electron, and Δ_{xy} is the Laplacian operator with respect to the x -, and y -axis coordinates. One
 58 of the most suitable approaches for the numerical calculation of the latter equation is the MS
 59 method [18].

60 2.1. Multislice method

61 The MS method developed by Cowley and Moodie [19], and later performed for fast com-
 62 putation by Ishizuka [11] and Rez [20] is one of the most efficient methods to solve the non-
 63 relativistic Schrödinger equation given by Eq. (1). In this method, the specimen potential is
 64 divided into many slices along the electron beam propagation. Each slice has to be thin enough
 65 to be considered as a weak phase object, which modifies only the phase of the incident wave.
 66 The potential between two consecutive slices is considered to be zero and the propagation of
 67 the electron wave within the slice is approximated by the Fresnel propagator, which involves a
 68 convolution in real space. The electron wave at any depth z_n can be calculated by repeated ap-
 69 plication of this process [11, 18]. The mathematical formalism of the multislice method can be
 70 expressed as

$$\psi_{n+1}(\mathbf{R}, z_{n+1}) = P(\mathbf{R}, \varepsilon) \otimes [T(\mathbf{R}, z_n)\psi_n(\mathbf{R}, z_n)] + \mathcal{O}(\varepsilon^2) \quad (3)$$

71 where $\mathbf{R} = (x, y)$ is the set of two-dimensional (2D) Cartesian coordinates and ε is the distance
 72 between the slices z_n and z_{n+1} ,

$$P(\mathbf{R}, \varepsilon) = \frac{1}{i\lambda\varepsilon} \exp\left(\frac{i\pi}{\lambda\varepsilon}(x^2 + y^2)\right) \quad (4)$$

73 is the Fresnel propagator, and

$$T(\mathbf{R}, z_n) = \exp\left(i\sigma \int_{z_n}^{z_n+\varepsilon} V(\mathbf{R}, z')dz'\right), \quad (5)$$

74 is the transmission function for the correspondent slice with $\sigma = 2\pi m\lambda/h^2$ the interaction param-
 75 eter. The 2D convolution operator (\otimes) is defined as

$$f(\mathbf{R}) \otimes g(\mathbf{R}) = \int f(\mathbf{R}')g(\mathbf{R} - \mathbf{R}')d^2\mathbf{R}'. \quad (6)$$

76 2.2. Frozen phonon method

77 The low-intensity diffuse background in between the normal diffraction peaks is strongly re-
 78 lated to the atomic vibration [21]. This background intensity that will be referred to as thermal
 79 diffuse scattering (TDS) produces effects in both diffraction patterns and ADF STEM images. In
 80 the standard multislice calculation, this effect is neglected [22]. The best way to describe TDS is
 81 by using the frozen phonon model [21, 23]. This model has been proved in a rigorous way to be
 82 fully equivalent to a full quantum mechanical treatment of the inelastic phonon scattering [24],
 83 and has been demonstrated to result in a good match with the experiment even for thicker speci-
 84 mens [25] and specimens containing heavy atoms [26]. This method is based on a basic classical
 85 description in which each electron sees a different configuration of atoms displaced from their

86 equilibrium positions. The resulting image intensity is obtained by averaging the simulated im-
 87 ages performed for a certain number of configurations. The displacement of the atoms due to the
 88 vibration of the specimen can be calculated by molecular dynamics, DFT calculations, or using
 89 a random number generator with a Gaussian distribution which is the equivalent to the Einstein
 90 model (FL) of the density of states for phonons [18].

91
 92 Assuming that the total specimen potential $V(\mathbf{r}, t)$ and the electron wave $\psi(\mathbf{r}, t)$ are time-
 93 dependent, these equations can be written as [24, 27]:

$$V(\mathbf{r}, t) = \langle V(\mathbf{r}) \rangle + W(\mathbf{r}, t) \quad (7)$$

$$\psi(\mathbf{r}, t) = \langle \psi(\mathbf{r}) \rangle + \delta(\mathbf{r}, t) \quad (8)$$

94 where $\langle \rangle$ is the average taken over time t . It is important to note that this should not necessarily
 95 refer to the real time. In general, it can refer to each state of the object. In repeated multislice
 96 calculations, it refers to a frozen phonon configuration. From Eqs. (7) and (8), it follows

$$\langle W(\mathbf{r}, t) \rangle = 0, \quad (9)$$

$$\langle \delta(\mathbf{r}, t) \rangle = 0. \quad (10)$$

97
 98 Using these assumptions, Van Dyck [24] has shown that the frozen phonon model allows us to
 99 split the total intensity into a coherent and an incoherent contribution. By taking the square of
 100 Eq. (8) and using Eq. (10), the total intensity at depth z can be calculated as

$$\langle |\psi(\mathbf{R}, z)|^2 \rangle = |\langle \psi(\mathbf{R}, z) \rangle|^2 + \langle |\delta(\mathbf{R}, z)|^2 \rangle \quad (11)$$

101 Note that the explicit time dependence has been dropped from here on in order to simplify the
 102 notation. The first term on the right-hand side corresponds to the coherent intensity (i.e. elastic
 103 scattering) and the second term corresponds to the incoherent intensity (i.e. inelastic scattering),
 104 respectively. This derivation also holds in Fourier space. Therefore, for each probe located at the
 105 position (x_k, y_l) , the intensity can be calculated by integrating the total intensity (coherent plus
 106 incoherent) over the detector:

$$f_{kl} = \int_{\text{detector}} \langle |\Psi(\mathbf{g}, z)|^2 \rangle d^2\mathbf{g}, \quad (12)$$

107 where $\mathbf{g} = (g_x, g_y)$ is a 2D vector in reciprocal space and $\Psi(\mathbf{g}, z)$ is the Fourier transform of
 108 $\psi(\mathbf{R}, z)$.

109 2.3. Absorptive potential method

110 The absorptive potential approximation [28, 11, 13], computed from e.g. the Weickenmeier
 111 and Kohl parametrization [29], is a quasi-coherent approach in which the distribution of the
 112 atomic displacements due to the thermal vibration of the atoms into the specimen is described by
 113 the convolution of the atomic scattering factors with a Gaussian function. The intensities of the
 114 STEM image are then calculated by using a modified, complex, projected potential $V(\mathbf{R})$ [11]:

$$V(\mathbf{R}) = V_r(\mathbf{R}) + iV_i(\mathbf{R}). \quad (13)$$

115 The diffuse intensity now results from the presence of an imaginary component $V_i(\mathbf{R})$, which is
 116 known as the absorptive potential. This potential is evaluated using the absorptive form factor
 117 defined in [30]. The real component, $V_r(\mathbf{R})$, corresponds to the normal electrostatic potential,
 118 which can be calculated using the elastic atomic scattering factors tabulated in [31]. Following
 119 [11], the total intensity can be calculated as the sum of both coherent and TDS contributions for
 120 each position of the probe (x_k, y_l) :

$$f_{kl} = I_{kl}^{coherent} + I_{kl}^{TDS}. \quad (14)$$

121 The coherent contribution is described by

$$I_{kl}^{coherent} = \int_{detector} |\Psi(\mathbf{g}, z)|^2 d^2\mathbf{g}, \quad (15)$$

122 where $\Psi(\mathbf{g}, z)$ is the Fourier transform of $\psi(\mathbf{R}, z)$, which can be computed using the multislice
 123 method where the potential is given by the complex potential defined by Eq. (13). The incoherent
 124 contribution is given by

$$I_{kl}^{TDS} = \sum_{n=1}^m \int |\psi_n(\mathbf{R}, z_n)|^2 V_n^{TDS}(\mathbf{R}) d^2\mathbf{R}, \quad (16)$$

125 where m refers to the total number of slices, $\psi_n(\mathbf{R}, z_n)$ is given by Eq. (3) using the complex
 126 potential defined by Eq. (13), and $V_n^{TDS}(\mathbf{R})$ can be derived from the absorptive potential $V_i(\mathbf{R})$
 127 following [11].

128 2.4. Statistical measurement precision

129 Ultimately, the precision with which unknown structure parameters can be estimated, such
 130 as the 2D positions of projected atom columns or 3D locations of individual atoms, is limited by
 131 noise. Indeed, due to noise, the pixel values that constitute the experimental images will fluctuate
 132 randomly from experiment to experiment. These pixel values, which we will from now on refer
 133 to as observations, can be modelled as random variables, characterized by a joint probability
 134 function (PF). In a STEM experiment, the observations are counting results, for which the PF can
 135 be modelled as a Poisson distribution. Based on the PF, an expression for the highest attainable
 136 precision with which structure parameters of the sample under study can be estimated in an
 137 unbiased way can be derived using the concept of Fisher information [32, 33]. This expression
 138 defines a lower bound on the variance of any unbiased estimator of a parameter and is known as
 139 the Cramér-Rao lower bound (CRLB). Consider a set of stochastic observations w_{kl} , $k = 1, \dots, K$,
 140 $l = 1, \dots, L$. Then, the vector w defined as

$$w = (w_{11}, \dots, w_{KL})^T \quad (17)$$

141 represents the column vector of these observations of dimension $K \times L$, where $K \times L$ corresponds
 142 to the dimension of each image. If the observations are assumed to be statistically independent,
 143 Poisson distributed variables, the probability that the observation w_{kl} is equal to ω_{kl} is given by
 144 [34]

$$\frac{\lambda_{kl}^{\omega_{kl}}}{\omega_{kl}!} \exp(-\lambda_{kl}) \quad (18)$$

145 with λ_{kl} the expected number of detected electrons at pixel (k, l) . The expected number of de-
 146 tected electrons per pixel position (k, l) equals

$$\lambda_{kl} = f_{kl} \frac{I\tau}{e} \quad (19)$$

with f_{kl} the fraction of electrons expected to be recorded by the detector, I the probe current in ampere, τ the recording dwell time for one pixel, and $e = 1.6 \times 10^{-19}$ C the electron charge. These expectation values can be simulated using either the FL model using Eq. (12) or the AP model using Eq. (14) within the MS algorithm. When assuming statistically independent observations, the probability $P(\omega; \beta)$ that a set of observations $w = (w_{11}, \dots, w_{KL})^T$ is equal to $\omega = (\omega_{11}, \dots, \omega_{KL})^T$ is the product of all the probabilities described by Eq.(18):

$$P(\omega; \beta) = \prod_{k=1}^K \prod_{l=1}^L \frac{(\lambda_{kl})^{\omega_{kl}}}{\omega_{kl}!} \exp(-\lambda_{kl}). \quad (20)$$

This function is the joint PF of the observations. Since the expectation values depend on the choice of the structure of the object under study, the unknown structure parameters β enter $P(\omega; \beta)$ via λ_{kl} . The expression for the joint PF enables one to compute the CRLB. The Fisher information matrix F for estimation of a set of unknown structure parameters β is defined as

$$F = -\mathbb{E} \left[\frac{\partial^2 \ln P(\omega; \beta)}{\partial \beta \partial \beta^T} \right] \quad (21)$$

where $\mathbb{E}[\]$ is the expectation operator. The expression between brackets is the Hessian matrix of $\ln P(\omega; \beta)$ of which the (p, q) th element is defined as

$$\frac{\partial^2 \ln P(\omega; \beta)}{\partial \beta_p \partial \beta_q} \quad (22)$$

where β_p and β_q correspond to the p and q th element of the vector β , respectively. The elements $F(p, q)$ may be calculated explicitly using Eqs.(19)-(22) [35]:

$$F(p, q) = \sum_{k=1}^K \sum_{l=1}^L \frac{1}{\lambda_{kl}} \frac{\partial \lambda_{kl}}{\partial \beta_p} \frac{\partial \lambda_{kl}}{\partial \beta_q}. \quad (23)$$

It is important to note that the dimension of the Fisher information matrix depends on the number of parameters to be estimated. Suppose that $\hat{\beta}$ is an unbiased estimator of β . The Cramér-Rao inequality then states that [36]

$$\text{cov}(\hat{\beta}, \hat{\beta}) \geq F^{-1} \quad (24)$$

where $\text{cov}(\hat{\beta}, \hat{\beta})$ is the variance-covariance matrix of the estimator $\hat{\beta}$, defined by its (p, q) th element $\text{cov}(\hat{\beta}_p, \hat{\beta}_q)$. Its diagonal elements are thus the variances of the elements of $\hat{\beta}$. The matrix F^{-1} is called the Cramér-Rao lower bound on the variance of $\hat{\beta}$. The Cramér-Rao inequality (24) expresses that the difference between the left-hand and right-hand member is positive semi-definite. A property of a semi-definite matrix is that its diagonal elements cannot be negative. This means that the diagonal elements of $\text{cov}(\hat{\beta}, \hat{\beta})$ will always be larger than or equal to the corresponding diagonal elements of the inverse of the Fisher information matrix. Therefore, the diagonal elements of F^{-1} define lower bounds on the variances of the elements of $\hat{\beta}$

$$\text{var}(\hat{\beta}_p) \geq \sigma_{\beta_p}^2 = F^{-1}(p, p) \quad (25)$$

where $F^{-1}(p, p)$ is the (p, p) th element of the inverse of the Fisher information matrix.

173 3. Simulation settings

174 In this paper, simulations of STEM images with the inclusion of the FL model and the AP
 175 model are performed using the MULTEM [37, 38] and STEMsim [13, 39] programs, respec-
 176 tively. Although both programs show the same results for simulations with FL calculations using
 177 the Weickenmeier and Kohl parametrization [29], the advantage of MULTEM with respect to
 178 STEMsim is the computation time. Especially since MULTEM uses the graphical processor unit
 179 (GPU) instead of the central processor unit (CPU), it is more time-efficient for this type of cal-
 180 culations. Simulations have been performed for isolated atomic columns and FCC structures of
 181 Cu, Ag, and Au atoms with a lattice parameter of 3.615 Å, 4.0853 Å and 4.078 Å, respectively.
 182 For the isolated columns, the distance between atoms in the column is chosen equal to the lattice
 183 parameter of their respective FCC structure.

184
 185 In order to study the annular dependence, simulations are performed for a detector covering
 186 the range from 40 to 160 mrad in steps of 2 mrad. Moreover, simulations are performed using
 187 three detectors as shown in table 1. In STEM image formation, the intensity of each pixel of the
 188 image is the result of the intensity produced by diffracted electrons over the detector plane and
 189 integrated over the detector geometry. In this study, simulations have been performed assuming
 190 symmetric and concentric annular detectors with an ideal detector sensitivity. The Debye-Waller
 191 factor for the three atom types has been calculated [40] at a temperature of 300 K and the defocus
 192 value has been adjusted to the Scherzer conditions. The other parameters are shown in table 1.
 193 For the FL simulations, 200 configurations have been computed using the Einstein model.

194

Table 1: Parameters for the MS simulations

Parameter	Symbol	Value
Annular detector 1	D_1 (mrad)	40-80
Annular detector 2	D_2 (mrad)	80-120
Annular detector 3	D_3 (mrad)	120-160
Debye-Waller factor Cu	(Å ²)	0.5747
Debye-Waller factor Ag	(Å ²)	0.7612
Debye-Waller factor Au	(Å ²)	0.7003
Acceleration voltage	(kV)	300
Defocus	(Å)	-14.03
FWHM of the source image	(Å)	0.8
Spherical aberration	C_S (mm)	0.001
Spherical aberration of 5th order	C_5 (mm)	0.0
Convergence angle	α_0 (mrad)	21.00
Numerical real space grid		1536×1536

195 4. Numerical results

196 In this section, both approximation methods used to include the TDS signal in STEM image
 197 simulations, that is, the FL and AP model, will be compared in terms of: a) *integrated intensity*
 198 and b) *precision* with which an atomic column can be located. These quantities are important

199 to determine the structure and chemical composition of the specimen when using STEM experi-
200 ments.

201 4.1. Integrated intensity

202 In this section, both the FL and the AP models will be compared in terms of the integrated
203 intensity that is produced by an atomic column. This integrated intensity corresponds to the
204 so-called scattering cross section [41], which has been shown to be a good measure to count
205 the number of atoms in an atomic column from a single STEM image [6, 42, 43, 44, 45]. It is
206 defined as the total scattered intensity integrated over the scanned area. Furthermore, the scanned
207 area will be selected in such a way that the atomic column will be placed in the centre in order
208 to collect most of the scattered intensity [46, 47]. The integrated intensity is defined as

$$I_{int} = \sum_k^K \sum_l^L f_{kl} \Delta x \Delta y, \quad (26)$$

209 with f_{kl} the fraction of electrons expected to be recorded by the detector at pixel (k, l) in a 2D
210 STEM image with $K \times L$ pixels. Furthermore, Δx and Δy is the pixel size along the x - and y -axis,
211 respectively (usually $\Delta x = \Delta y$).

212 The total intensity, calculated with the FL model is obtained by averaging the intensity of
213 different configurations given by equation (12). Here, the MS method treats the interaction be-
214 tween the electron and the rigorously displaced atoms as an elastic (coherent) scattering process
215 in which the scattered wave still interferes with the unscattered wave [48]. On the other hand,
216 the AP model describes the TDS intensity by including absorption in the dynamical equation of
217 the electron diffraction using a complex lattice potential, and calculates this intensity following
218 equation (14). In order to make a comparison between both methods, the integrated intensity
219 for three atom types (Cu, Ag and Au) will be investigated in three different ways. In 4.1.1, we
220 will analyse how both methods distribute the integrated intensity over the annular detectors as a
221 function of thickness. Next, in 4.1.2, the integrated intensity will be quantified for three detector
222 ranges of an isolated column. In 4.1.3, this procedure will be repeated to quantify the integrated
223 intensity of a column inside an FCC structure.
224

225 4.1.1. Distribution over the annular detector

226 Using equation (26), the integrated intensity produced by an isolated atomic column has
227 been calculated as a function of thickness. To perform the simulations, a super cell of length
228 $30 \times 30 \times L_{at}$ is considered with L_{at} the number of atoms in the column times the interatomic
229 distance. Therefore, STEM images have been simulated with a pixel size of 0.15 \AA over a square
230 region with a side length of 20 \AA . The atomic column with thickness up to 20 nm was placed in
231 the centre of the scanned region. The annular detector covers a range from 40 to 160 mrad in
232 steps of 2 mrad . For low angles, we refer to the lower values of this range. For each ring (an-
233 nular detector of 2 mrad wide), the integrated intensity was computed. In this manner, it can be
234 investigated how both methods distribute the intensity over the annular detector for atoms with
235 different scattering factors. The results of these distributions are shown in figure 1.
236

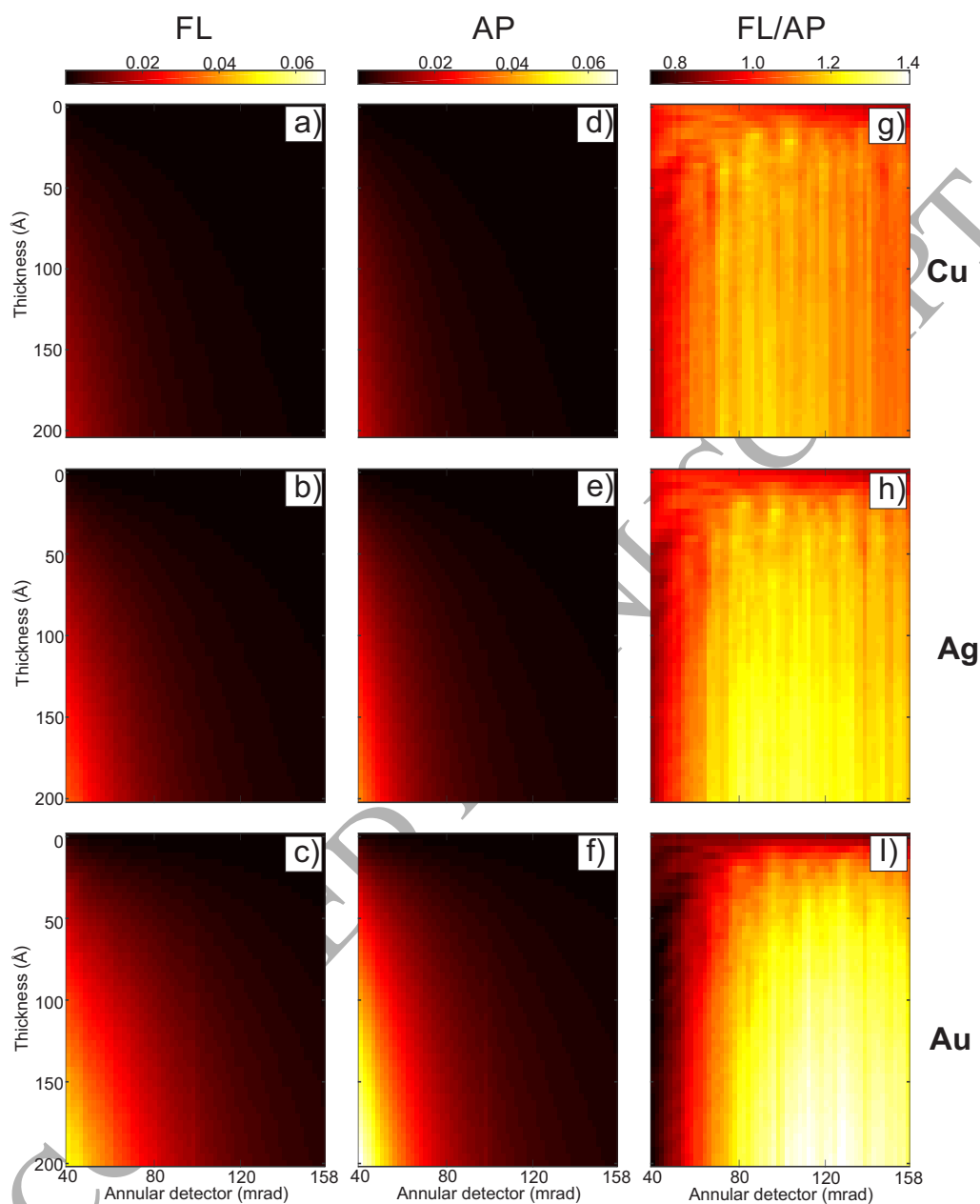


Figure 1: Distribution of the STEM integrated intensity over the detector range as a function of the thickness for an isolated column of atoms of Cu, Ag, and Au. The detector covering the range from 40 to 160 mrad was subdivided into 60 rings of 2 mrad each. The integrated intensity was calculated for each ring as a function of thickness. Figures a-c) show the results performed using the FL method. Figures d-f) show the results performed using the AP method. Figures g-i) show the proportion of the FL with respect to the AP method (FL/AP).

237 Figures 1a-c and 1d-f show the results of the distribution of the integrated intensity computed
 238 from simulations performed using the FL and the AP models, respectively. From these figures,

with equal scale-bar for the intensity, we can observe that the amount of intensity produced for both methods is different. The sensitivity of this difference between both methods may be a consequence of a break-down of the local approximation for the TDS absorption potential [49, 50] which suggests that the effect should be more pronounced in smaller detectors, in our case narrower detectors. This difference seems to change as a function of: a) thickness, b) detector range, and c) atom type. The ratio between intensities generated using both methods (FL/AP) is illustrated in figures 1g-i. For most detector angles and thickness values, the FL model results into higher intensities as compared to the AP model. Only for a small part of the detector range (low angles), the AP model has equal or higher intensity as compared to the FL model. These figures also demonstrate how the ratio between both methods depends on the atom type suggesting that this ratio increases as a function of the scattering factor. For example, the maximum ratio of the intensity for Au atoms (strong scattering factor) is larger as compared to the maximum ratio of intensities for atoms of Ag (medium scattering factor) and Cu (weak scattering factor).

More particularly, when comparing both methods for the three atoms types, we observe:

- *For atoms of Cu:* figures 1a,d show that both methods have a similar distribution of the scattered intensity. However, the ratio between both methods is not linear as we can see more clearly in figure 1e where larger differences between both methods are observed in the range between 70 to 120 mrad. For this atom type, the ratio between both models oscillates in the range from 0.9 to 1.2.
- *For atoms of Ag:* figures 1b,e show that the AP model produces more scattering than the FL model for low angles (lower than 50 mrad). For higher angles, the difference between both methods starts to increase, especially in the range from 80 to 120 mrad where the FL model results into higher intensities as compared to the AP model. This is shown in figure 1h. For this atom type, the ratio between both models oscillates in the range from 0.9 to 1.3.
- *For atoms of Au:* figures 1c,f show a similar behaviour for atoms of Ag although with even larger ratios between both methods. Figure 1i shows this behaviour more clearly. The largest difference between both methods is found in the range from 100 to 150 mrad and for thickness values larger than 100 Å. The ratio between both models oscillates in the range from 0.7 to 1.4. When comparing these results with the results shown in figures 1g and 1h, we can see that the detector range, where the AP model results into larger intensity values than the FL model increases as a function of scattering factor.

Based on this comparison, we can conclude that both models are only in good agreement in a very small detector range. This range depends on the atom type. Furthermore, the comparison shows that the AP model results into larger intensity values than the FL model for low angles. For larger angles, the FL model results into more scattering than the AP model. This distribution suggests that for detectors of realistic size, the integrated intensity depends on the collected detector range. For example, if we compute the integrated intensity for Au atoms using a detector ranging from 40 to 80 mrad, both methods will show similar results because the difference for low angles will be compensated with the difference observed for higher angles.

4.1.2. Integrated intensities for isolated columns

In the previous subsection, the distribution of the integrated intensity as a function of detector angle and thickness has been computed for both models. In order to quantify the difference of the

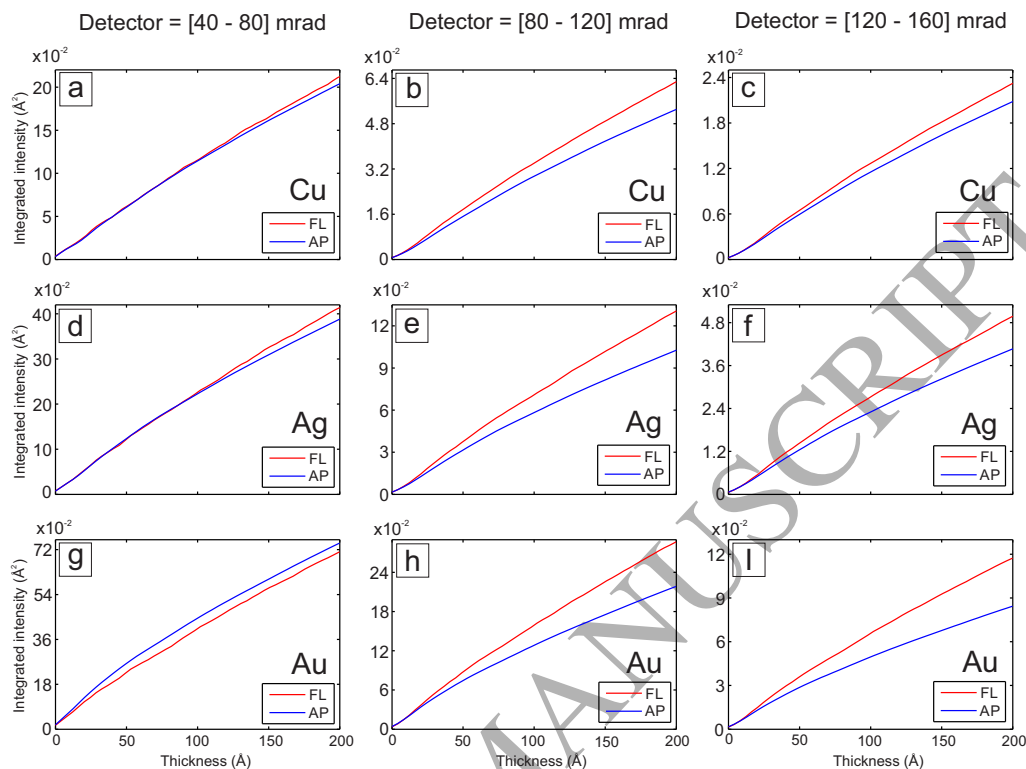


Figure 2: Integrated intensity as a function of thickness for an isolated column of atoms of Cu, Ag, and Au. The integrated intensity was calculated from simulations performed using the MS algorithm with the inclusion of the frozen phonon (red line) and absorptive potential (blue line). Figures a,d,g) correspond to the detector of 40 to 80 mrad; figures b,e,h) correspond to the detector of 80 to 120 mrad; and figures c,f,i) correspond to the detector of 120 to 160 mrad.

283 integrated intensity between both models for realistic detector settings, we proceed in the same
 284 way as in the previous subsection. We use the three detectors D_1 , D_2 , and D_3 defined in table 1
 285 with all other parameters kept constant. The results are shown in figure 2, where the integrated
 286 intensity is plotted as a function of thickness for an atomic column consisting of Cu, Ag, and Au
 287 atoms. From these figures, we conclude that:

- 288 • for detector D_1 (first column of figure 2), both methods are in good agreement for small
 289 thicknesses with values around 140 Å, 100 Å, and 20 Å for atoms of Cu, Ag, and Au,
 290 respectively. For larger thicknesses, the FL model produces more intensity than the AP
 291 model for Cu and Ag, whereas for Au, the effect is opposite.
- 292 • for detector D_2 (second column of figure 2), both methods are in good agreement up to
 293 thicknesses around 20 Å for the three atom types. For larger thicknesses, the FL model
 294 produces more intensity than the AP model. The difference between both methods scales
 295 with the thickness and the scattering factor.
- 296 • for detector D_3 (third column of figure 2), both methods show the same behaviour as for
 297 detector D_2 .

298 Assuming the FL as the most accurate model, we can conclude from the results shown in
 299 figure 2 that for detector D_1 , the AP model underestimates the integrated intensity for Cu and
 300 Ag, whereas it overestimates for Au. Despite these differences, the fact that both methods show
 301 similar results for detector D_1 does not mean that both methods are distributing the intensity in
 302 the same way. This is shown in figures 1g-i. In this detector range, there is a compensation of
 303 the intensity. For angles close to 40 mrad, the AP model scatters more intensity and for angles
 304 close to 80 mrad the FL model scatters more intensity. For detectors D_2 and D_3 , the AP model
 305 underestimates the intensity. This effect seems to increase as a function of thickness and also as
 306 a function of the scattering factor. A possible explanation for this observation can be found in
 307 the fact that the FL includes multiple elastic and TDS scattering to all orders [22] whereas the
 308 AP assumes that, once thermally scattered, the electrons are not scattered again [25].

309
 310 The impact of the observed differences in intensity between both models will depend on the
 311 purpose for which the intensity is used. For example, if one wants to quantify the location of
 312 atomic columns from 2D STEM images, the difference in intensity between both methods is
 313 perhaps not important. However, if the analysis is focused on the quantification of the number of
 314 atoms or atom type, this difference can introduce wrong values. In equations (11) and (16),
 315 the intensity is related to the scattering factor amplitude of the atom type. From the results,
 316 we can observe that atoms with high scattering factor scatter more intensity to higher angles as
 317 compared to atoms with weak scattering factor. One should realize that this study is based on an
 318 isolated column and does not take into account the effect caused by cross-talk produced by the
 319 neighbouring columns [51, 52]. Therefore, in the next subsection we will analyse this effect for
 320 more realistic specimens.

321 4.1.3. Integrated intensities for FCC structures

322 To compare the integrated intensity between both models for more realistic specimens, where
 323 the cross-talk produced by neighbouring columns is taken into account, an FCC structure of Cu,
 324 Ag, and Au atoms with lattice parameters of 3.615 Å, 4.0853 Å, and 4.078 Å, respectively, were
 325 assumed. The simulation were performed using a super cell of $36.1 \times 36.1 \times L_{uc}$, $36.7 \times 36.7 \times L_{uc}$
 326 and $36.7 \times 36.7 \times L_{uc}$ for atoms of Cu, Ag and Au, respectively, where L_{uc} is equal to the number
 327 of unit cells along the beam direction times the interatomic distance. We used the detectors D_1 ,
 328 D_2 , and D_3 , and the parameters mentioned in table 1. The integrated intensity was computed

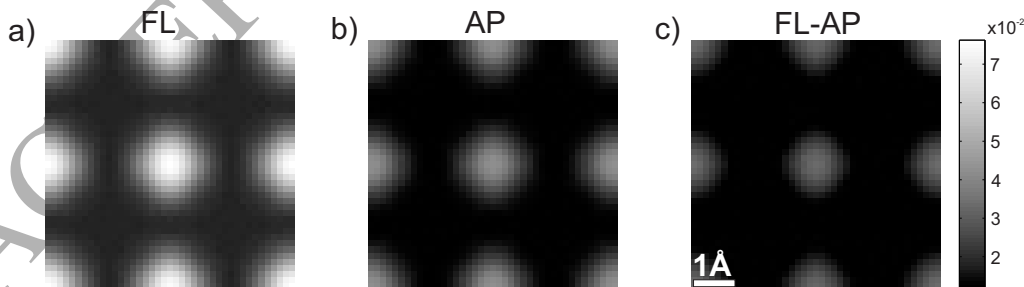


Figure 3: Simulated STEM images of an FCC structure of Au atoms along the [001] zone-axis for a thickness of 20 nm and a detector ranging from 120 to 160 mrad, using the MS algorithm with the inclusion of a) the frozen lattice model, and b) the absorptive potential approximation. Figure (c) is the difference between the frozen lattice and the absorptive potential approximation. All images are plotted on the same scale.

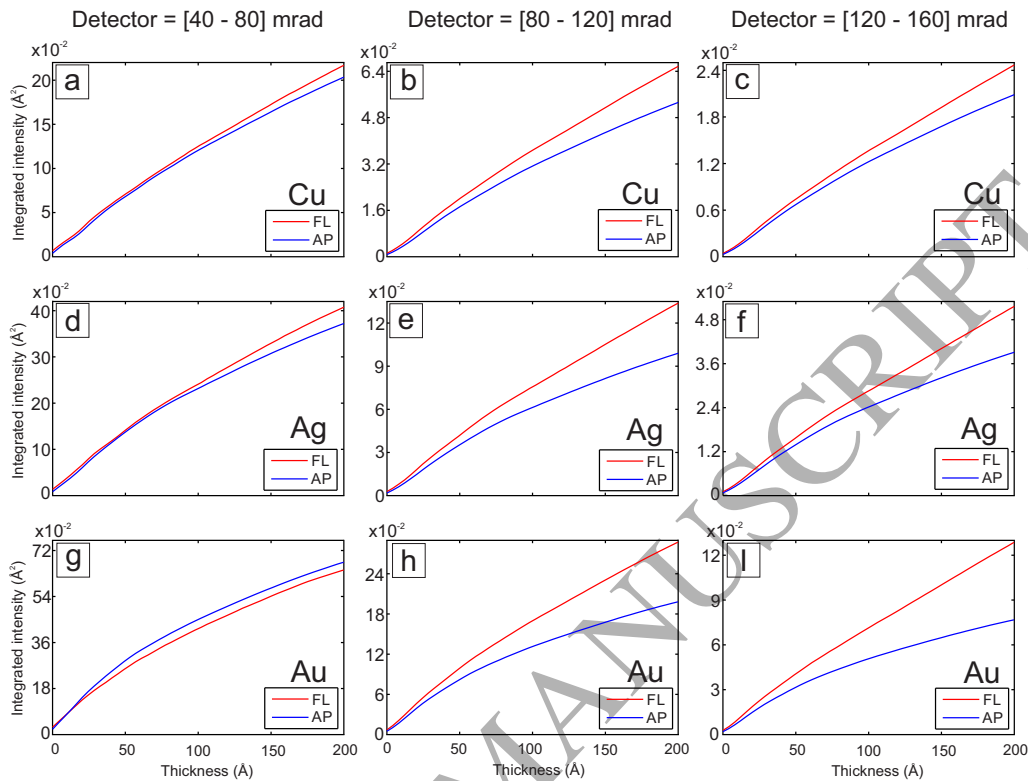


Figure 4: Integrated intensity as a function of thickness for an atomic column of an FCC structure of atoms of Cu, Ag, and Au. The integrated intensity was calculated from simulations performed using the MS algorithm with the inclusion of the FL (red line) and AP approximation (blue line). Figures a,d,g) correspond to the detector of 40 to 80 mrad; figures b,e,h) correspond to the detector of 80 to 120 mrad; and figures c,f,i) correspond to the detector of 120 to 160 mrad.

329 over a scanned area equivalent to one unit cell with a pixel size of 0.145 \AA along the $[001]$
 330 zone-axis as shown in figure 3. In order to compare the integrated intensity with respect to one
 331 atomic column, the integrated intensity of one unit cell is divided by the number of projected
 332 atomic columns in one projected unit cell, which in this case equals 4. Using this criterion, the
 333 integrated intensity was computed as a function of thickness. The first, second and third column
 334 of figure 4 show the results of the integrated intensity as a function of thickness for the three
 335 atom types for detectors D_1 , D_2 and D_3 , respectively. When comparing these results with the
 336 integrated intensities computed for an isolated column, as shown in figure 2, only small differ-
 337 ences are observed. In general the behaviour is the same for the three detectors and for the three
 338 atom types. Although neighbouring columns do not cause significant deviations in the integrated
 339 intensity, this effect depends on the detector range and thickness [53].

341 This study has also been performed for Au atoms with an acceleration voltage of 80 kV and
 342 200 kV keeping the same input parameters and using the same equivalent semi-aperture angle
 343 and detectors used at 300 kV. At 80 kV, a semi-aperture angle of 44.5 mrad and equivalent detec-
 344 tors D_1 , D_2 , and D_3 of $[84.9-170.3] \text{ mrad}$, $[170.3-256.7] \text{ mrad}$ and $[256.7-344.7] \text{ mrad}$ have been
 345 considered, respectively. At 200 kV, these values are equal to a semi-aperture angle of 26.7 mrad

and detectors of [50.9-101.9] mrad, [101.9-153.1] mrad and [153.1-204.3] mrad. The results at 80 kV and 200 kV are shown in figure 5. From this figure we can observe that at these lower voltages, both models show the same trend but the difference between both models increases as a function of thickness for the equivalent detector D_1 . For detectors D_2 and D_3 , the FL model has a steeper slope as compared to the AP model. For thicknesses up to about 10 nm, the intensities produced by the AP model are larger than those of the FL model. For larger thicknesses, the FL model results into larger intensities. Furthermore, the difference scales with thickness. As compared to the results obtained at 300 kV, larger differences are obtained at those lower acceleration voltages.

In general, the results of this section show that the AP model may lead to considerable differences as compared to the FL model. Especially for detectors D_2 and D_3 , the intensity is underestimated as a function of thickness and atom type. Therefore, we need to be careful when using the AP model to quantify the number of atoms or atom type. It is also important to mention that this result cannot be generalized to all atom types. Table 2 shows the maximum difference in number of atoms between the FL and the AP model up to a thickness of 20 nm corresponding to 55 atoms of Cu and 49 atoms of Ag and Au in the column. Figure 4 shows that the AP model underestimates the number of atoms with respect to the FL model with only one exception for detector D_1 , where the intensity is overestimated in the presence of Au atoms.

4.2. The ultimate precision

In this section, both the FL and AP models will be compared in terms of the ultimate precision with which an atomic column can be located in 2D from images acquired using HAADF

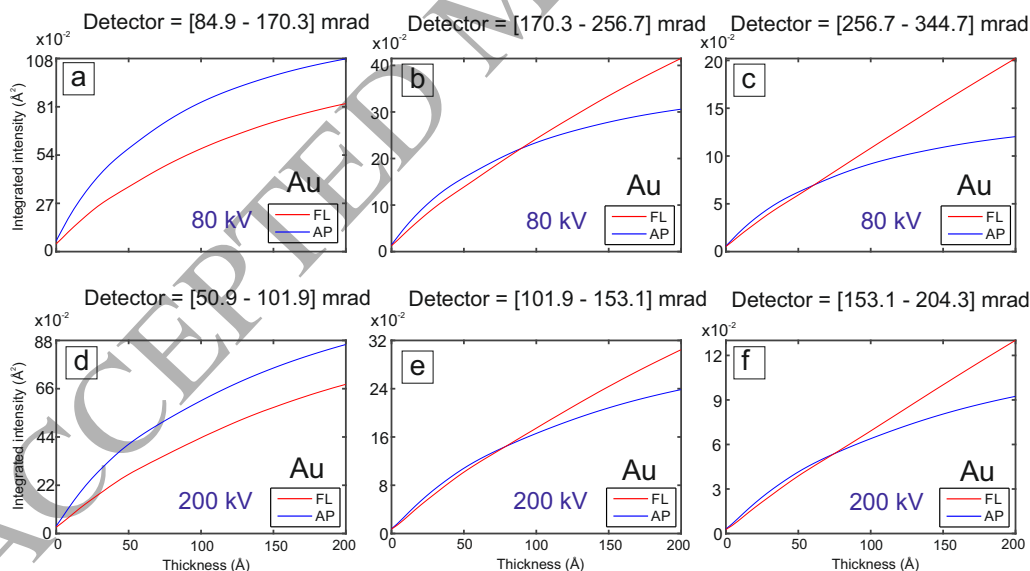


Figure 5: Integrated intensity as a function of thickness for an atomic column of an FCC structure of Au atoms. The integrated intensity was calculated from simulations performed using the MS algorithm with the inclusion of the FL model (red line) and the AP approximation (blue line). Figures a-c) correspond to an acceleration voltage of 80 kV with a detector range of [84.9-170.3] mrad, [170.3-256.7] mrad, and [256.7-344.7] mrad; figures e-g) correspond to an acceleration voltage of 200 kV with a detector range of [50.9-101.9] mrad, [101.9-153.1] mrad, and [153.1-204.3] mrad.

Table 2: Maximum difference in assigning the number of atoms when using the FL and AP model up to a thickness of 20 nm for each detector.

	D_1	D_2	D_3
Cu	4	12	10
Ag	5	14	14
Au	5	17	22

STEM [2, 54]. The ultimate precision, i.e. the lower bound on the standard deviation with which unknown structure parameters can be estimated unbiasedly, is given by the elements of the diagonal of the inverse of the Fisher information matrix F , defined by equation (23). From this equation, it is clear that the elements of the Fisher information matrix have to be calculated using the derivatives of the parametric model of the intensity observations λ_{kl} given by equation (19) with respect to the position coordinates of the projected atomic columns. In this study, the parametric model for the intensity observations λ_{kl} is simulated using the MS method.

As mentioned in section 2.1, the MS method is a numerical solution of the Schrödinger equation. In order to calculate the partial derivatives, additional sets of MS simulations are required in which a single atomic column is shifted along an axis. For example, for the derivative of an atomic column with respect to the x -coordinate, this column is displaced along the x -axis. The partial derivatives are then approximated using the following expression:

$$\lambda'(x) \approx \frac{\lambda(x+h) - \lambda(x)}{h} \quad (27)$$

where h is the shift of the column from its regular position along the x -axis. Similarly, the derivatives with respect to the y -axis can be calculated. The comparison between the FL and the AP models will be done in two ways. First, the ultimate precision to locate an isolated column of gold atoms from 2D STEM images is investigated. Next, the ultimate precision to locate a column inside an FCC structure is studied. For both cases, it will be investigated if the FL and AP models lead to the same results for the ultimate precision. For these calculations, the convergence of the derivatives given by equation (27) was analysed as a function of the displacement h , the number of configurations in the FL model, and the pixel size of the images. In this manner, optimal values were found with $h = 2$ pm, 200 FL configurations, and a pixel size of 0.35 Å.

4.2.1. Isolated column

From equation (23), it can be seen that the calculation of the Fisher information matrix requires the derivatives of the expectation model λ_{kl} with respect to the unknown parameters. In this case, the unknown parameters are the projected x and y coordinates of an isolated atomic column given by the vector

$$\boldsymbol{\beta} = (\beta_x, \beta_y). \quad (28)$$

Because of the cylindrical symmetry of the image intensity distribution of an atomic column, the derivatives with respect to the x - and y -axis are the same. Therefore, the Fisher information matrix simplifies to:

$$F = \begin{bmatrix} F_{11} & F_{12} \\ F_{12} & F_{22} \end{bmatrix}. \quad (29)$$

398 From equation (24) it follows that the CRLB on the variance, that is, $\sigma_{\beta_x}^2$ or $\sigma_{\beta_y}^2$, is given by the
 399 corresponding diagonal element of F^{-1} :

$$\sigma_{\beta_x}^2 = \sigma_{\beta_y}^2 = F^{-1}(1, 1). \quad (30)$$

400 The square root of the values of equation (30) gives us a lower bound on the standard deviation
 401 $\sigma = \sigma_{\beta_x} = \sigma_{\beta_y}$.

402

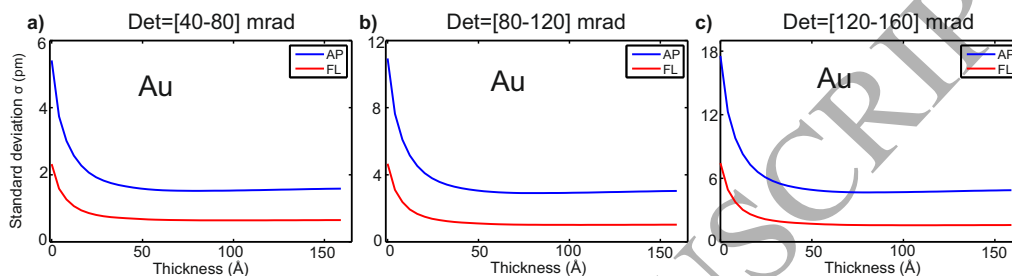


Figure 6: The ultimate precision σ to locate an isolated column of gold atoms as a function of thickness from simulated STEM images performed using the MS algorithm with the inclusion of the FL model (red line) and the AP model (blue line) for three detectors: a) [40-80] mrad, b) [80-120] mrad, and c) [120-160] mrad.

403 The CRLB has been computed for the FL and AP using a square region of 12.234 \AA with a
 404 pixel size of 0.3398 \AA for the atomic column at the centre of this region. An incident electron
 405 dose of $21652 e^-/\text{\AA}^2$ was used corresponding to a beam current of 40 pA and pixel dwell time
 406 $\tau = 10 \mu\text{s}$. The results for the precision are shown in figure 6 as a function of thickness. From this
 407 figure we can observe that the ultimate precision has the same behaviour for both methods for
 408 the three detectors. The precision improves as a function of thickness but beyond a certain value
 409 the gain in precision is marginal. For higher angles, the precision decreases i.e. the standard
 410 deviation increases. However, when comparing the results of both methods, the FL model shows
 411 a better precision for the three detectors as compared to the AP model. The difference between
 412 both methods is approximately constant with thickness. It is important to note that the precision
 413 is different for both methods even for the detector D_1 where similar results for the integrated
 414 intensities were found. Figure 2(g) shows that the AP model scatters more intensity than the FL
 415 but in terms of precision the FL model predicts a better precision as shown in figure 6(a). The
 416 reason for this is that the distribution of the intensity over the scanned area is different for both
 417 methods.

418 4.2.2. FCC structure

419 In section 4.2.1, the ultimate precision to locate an atomic column in 2D was computed for an
 420 isolated column. In order to compute this theoretical limit on the precision for an atomic column
 421 where its intensity is affected by the cross-talk of the neighbouring columns, an FCC structure
 422 was assumed. The precision also depends on the atom types. Calculations were therefore per-
 423 formed for both the AP and the FL models using the same settings as for the integrated intensity
 424 in section 4.1.3.

425

426 Figure 7 shows the results of the ultimate precision as a function of thickness for the three
 427 atom types. From this figure, the precision with which a column of Cu atoms can be located

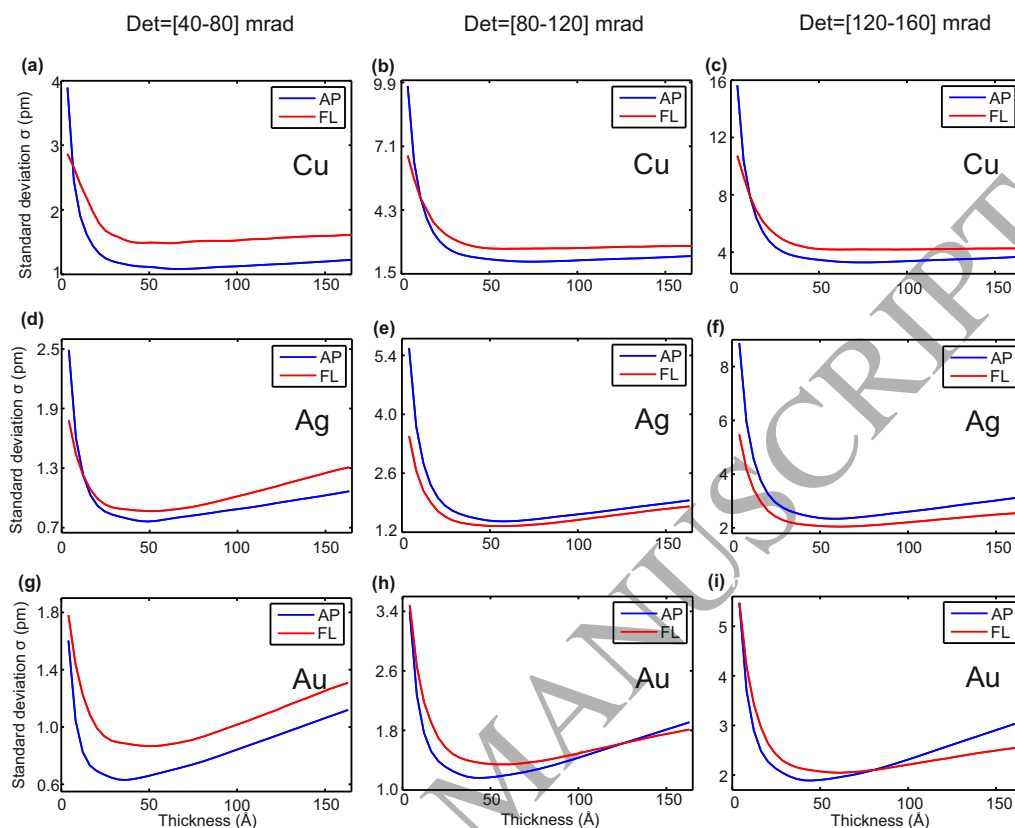


Figure 7: The ultimate precision to locate the central atomic column of Cu, Ag, and Au atoms in an FCC structure using the collected intensity of three detectors: a,d,g) [40-80] mrad. b,e,h) [80-120] mrad. c,f,i) [120-160] mrad. The precision was computed from simulated STEM images performed using the MS algorithm with the inclusion of the FL (red line) and AP approximation (blue line).

428 shows a similar behaviour for both methods. The precision improves as a function of thickness.
 429 However, beyond a certain value this gain is only marginal. For Ag and Au, the precision first
 430 improves as a function of thickness and beyond a certain value the precision starts to decrease.
 431 This behaviour is more pronounced for Au than for Ag. These results show that the behaviour
 432 of the ultimate precision to locate an atomic column from 2D STEM images for the three atom
 433 types is strongly related to their scattering factor amplitude. For atoms with a small scattering
 434 factor amplitude such as Cu, the intensity is scattered close to the location of the atomic col-
 435 umn position and therefore the contribution due to crosstalk is small. For atoms with a medium
 436 scattering factor such as Ag, the effect of crosstalk starts to make an influence on the calculation
 437 of the precision. For atoms with a strong or high scattering factor amplitude, such as Au, the
 438 influence of crosstalk is even more pronounced in the calculation of the precision.
 439

440 From figure 7, it may also be observed that the precision differs for both models. For atoms
 441 of Cu, the AP shows a better precision as compared to the FL model for thicknesses larger than
 442 1 nm for the three detector ranges. This difference increases as a function of the angles, i.e.

443 detectors with higher angles result into a larger difference for the precision. For atoms of Ag, the
444 same behaviour is presented for detector D_1 . For detectors D_2 and D_3 , the FL presents a better
445 precision as compared to the AP model for all thicknesses. For atoms of Au, the behaviour of
446 the precision for detector D_1 is the same as presented for atoms of Cu. For detectors D_2 and
447 D_3 , the AP shows a better precision for small thicknesses, and the FL for larger thicknesses. It
448 is important to mention that the attainable precision with which atomic column positions can be
449 measured, can be used to optimize the settings of the electron microscope [55, 56]. The observed
450 differences between the predicted precision for both methods shown in figure 7 is small enough
451 to accurately predict the optimal settings and to get an accurate prediction of the precision that
452 can ultimately be attained.

453

454 5. Conclusions

455 In this work, two of the most popular methods used to simulate STEM images, the frozen
456 phonon and the absorptive potential model, were compared in terms of the integrated intensity
457 and the theoretical limits with which an atomic column can be located in 2D based on the acqui-
458 sition of HAADF STEM images.

459

460 The integrated intensity was computed by integrating the total scattered intensity over the
461 scanned area. The results show a similar trend of the intensity as a function of thickness but
462 with different values for both models in the cases of an isolated atomic column and an atomic
463 column within an FCC structure. For the detector ranging from 40 to 80 mrad the difference of
464 the integrated intensity between both models is small especially for small thicknesses. For the
465 detectors ranging from 80 to 120 mrad and from 120 to 160 mrad, this difference increases as a
466 function of thickness and atom type. This means that atoms with a strong scattering factor results
467 into a larger difference in the integrated intensity. From this comparison, the results suggest that
468 we need to be careful when using the absorptive potential model for quantification when using
469 the integrated intensity because for high angles and large thicknesses this model underestimates
470 the integrated intensity.

471

472 Using the concept of the Cramér-Rao lower bound, the ultimate precision with which an
473 atomic column can be located from 2D HAADF STEM images has been computed for an isolated
474 column of Au atoms and for an atomic column within an FCC structure of Cu, Ag, and Au atoms.
475 For an isolated atomic column of Au atoms, the precision improves as a function of thickness,
476 but beyond a certain value, the gain in precision is marginal for both methods. However, for all
477 thicknesses, the frozen phonon predicts a better precision as compared to the absorptive potential
478 model. For the atomic column of an FCC structure, the ultimate precision depends on the atom
479 type and detector range. For the detector ranging from 40 to 80 mrad, the absorptive potential
480 shows a better precision with respect to the frozen phonon model for the three atom types. For the
481 detectors ranging from 80 to 120 mrad, the results for both methods are similar. The difference
482 between both methods are in the picometre scale for the simulation settings used in this paper.

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